

**Attorney Docket No. 081468-0306313**  
**Client Reference: P-1699,000-US**

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:     Robrecht De Weerd

Application No.:     Not Yet Assigned  
Filed:                October 9, 2003

Confirmation No:    Not Yet Assigned  
Group No.:          Not Yet Assigned  
Examiner            Not Yet Assigned

For:     Lithographic Apparatus and Device Manufacturing Method

**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

**APPLICATION DATA SHEET**  
**37 C.F.R. § 1.76**

**BIBLIOGRAPHIC DATA**

**1. Applicant information**

First applicant: Robrecht DE WEERDT  
Citizenship: Belgium  
Residence: Minderhoutdorp 33, Hoogstraten 2322, BELGIUM

**2. Correspondence information**

Correspondence for this application should be addressed as follows:

Customer No.: 00909

**3. Application information**

Title of Invention: Lithographic Apparatus and Device Manufacturing Method

Docket number assigned to this application: 081468-0306313

Suggested Classification:    Class:  
                                  Subclass:

Technology Center to which subject matter is assigned:

Total number of drawing sheets: 9

Type of application:

Utility

Application is to be published. Suggested drawing figure for publication:

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Secrecy order under § 5.2:

This application does not disclose subject matter of an application which is under a secrecy order pursuant to § 5.2.

**4. Representative information**

The following have a power of attorney or authorization of agent in this application:

Customer No.: 00909

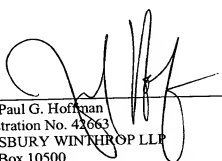
**5. Assignee information**

The assignee(s) of this application is/are:

ASML Netherlands B.V.  
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Veldhoven, NL 5503-LA  
THE NETHERLANDS

Extent of interest of assignee in application:

Date: October 9, 2003



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## **Addendum**

**Invention Title**

**Lithographic Apparatus and Device Manufacturing Method**